



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : Confirmation No. 9191

Makoto AKIZUKI et al. : Docket No. 2001-1897

Serial No. 10/025,899 : Group Art Unit 1762

Filed December 26, 2001 : Examiner B. Pianalto

**METHOD FOR FORMING GAS CLUSTER AND  
METHOD FOR FORMING THIN FILM**

**PETITION FOR EXTENSION OF TIME**

Assistant Commissioner for Patents,  
Washington, DC 20231

THE COMMISSIONER IS AUTHORIZED  
TO CHARGE ANY DEFICIENCIES  
UPON THIS PAPER TO DEBIT  
DEPOSIT ACCOUNT NO. 23-0975

Sir:

Petition hereby is made for a three month extension of time to respond to the communication of August 7, 2002.

The fee of \$930.00 is

(X) submitted herewith.  
( ) to be charged to Deposit Account No. 23-0975. A duplicate copy of this Petition is enclosed.  
( ) Small entity status of this application is established by a Small Entity Status Assertion which  
( ) is enclosed.  
( ) has been previously submitted.

Respectfully submitted,

Makoto AKIZUKI et al.

By

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